

**REMARKS**

The Examiner's Office Action of January 15, 2003 has been received and its contents reviewed. The Examiner is thanked for the consideration given to the application and for the suggested amendment in the Office Action.

By the above actions, claims 76, 79, 80, 83, 84, 88, 91, 93 and 97 have been amended. Accordingly, claims 76-102 are pending for consideration, of which claims 76, 80, 84, 88, and 93 are independent. In view of these actions and the following remarks, reconsideration of this application is now requested.

Applicants would like to bring to the Examiner's attention that the Amendment filed November 6, 2002 erroneously include two claims that are numbered as 97. The second occurrence of claim 97 has been amended, as shown above. Applicants will amend the claims to correct this error in a future Amendment.

Referring now to the detailed Office Action, in response to the rejection in section 2 in page 2 of the Office Action, Applicants have amended the specification as suggested by the Examiner to add the acronym "CPU" in the specification, as shown above.

In response to the rejection in section 3 in page 2 of the Office Action, Applicants have amended claims 79, 83, 91, 92, and 97 as shown above, to delete the feature of "layer of the semiconductor film" to overcome the lack of antecedent rejection. With respect to the use of undefined abbreviations or acronyms, Applicants have amended the specification, as discussed above. Hence, the recitation of "CPU" is now proper. With respect to claim 88, Applicants respectfully submit that the language "improved" is not found in the claim.

In response to the rejections in sections 4 and 5 in page 3 of the Office Action, Applicants have amended claims 76, 80, 84, 88, and 93, as shown above. Particularly, Applicants further specify in the claims that the semiconductor film is irradiated with a laser light to crystallize the same.

In response to the rejections in sections 6, 7, and 8 of the Office Action, Applicants respectfully submit that an example of TFT formed by not using a metal element is supported by the specification page 43, lines 14-25, and that, from this description, the TFT formed by not using a metal element is associated with laser irradiation process. Also, subsequent processes

such as light annealing or the like are supported by SUMMARY OF THE INVENTION. Therefore, the Examiner's contention of New Matter is not appropriate.

With respect to section 9 in page 6 of the Office Action, the reference to a non-statutory double patenting rejection appears incomplete and not relevant. Hence, Applicants are not responding to section 9 of the Office Action.

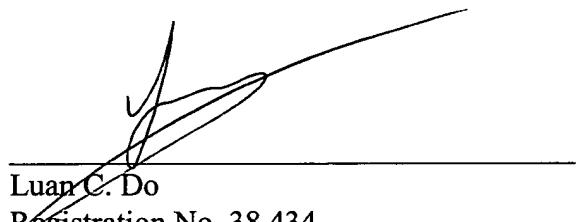
With respect to sections 10 and 11 in pages 7-12 of the Office Action, claims 76-102 stand rejected under 35 U.S.C. §103(a) as unpatentable over Ohtani et al. (U.S. Patent No. 5,543,352 – hereafter Ohtani) in view of Zhang et al. (U.S. Patent No. 5,529,937 – hereafter Zhang '937), or vice versa, optionally in view of Liu et al. ('826 – hereafter Liu) or Zhang et al. ('291 – hereafter Zhang '291), as applied in Paper #46. To the best of Applicants' understanding of the Examiner's reasoning, it appears that the Examiner's rejection relies on the step of using anneal with laser or IR after patterning and doping in Ohtani, Zhang et al.('937), and Mitanaga. In response to the rejection, Applicants have amended claims 76, 80, 84, 88, and 93, as shown above, to further clarify the claim language and to distinguish over the cited prior art references. Particularly, as amended, the pending claims relates to the laser irradiation and subsequent annealing before patterning a semiconductor film. As Zhang '937 and Mitanaga are deficient in the above-mentioned feature, their combination with other cited prior art references would not be proper.

In view of the amendments and arguments set forth above, Applicants respectfully request reconsideration and withdrawal of all the pending rejections.

While the present application is now believed to be in condition for allowance, should the Examiner find some issue to remain unresolved, or should any new issues arise which could be eliminated through discussions with Applicants' representative, then the Examiner is invited to contact the undersigned by telephone in order that the further prosecution of this application can thereby be expedited.

Respectfully submitted,

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